

Supplemental Information

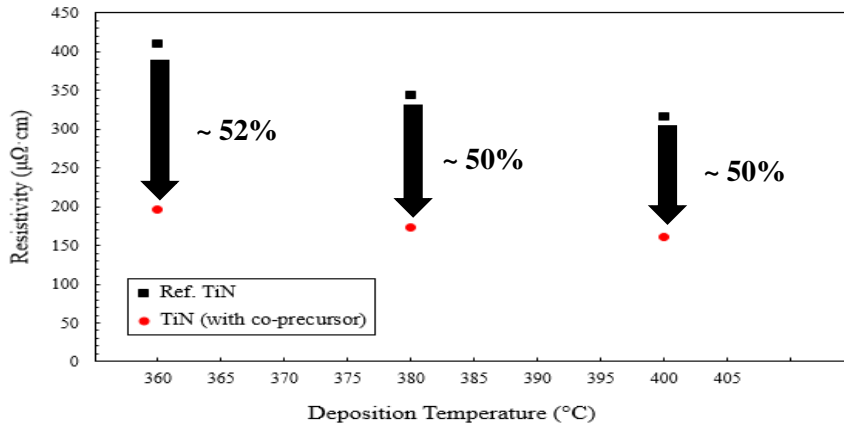


Fig. 1: Electrical resistivity of Ref. TiN (without co-precursor) and TiN (with co-precursor) at different deposition temperatures

Electrical Properties of High-*k* Oxide (HfO₂) Thin Film

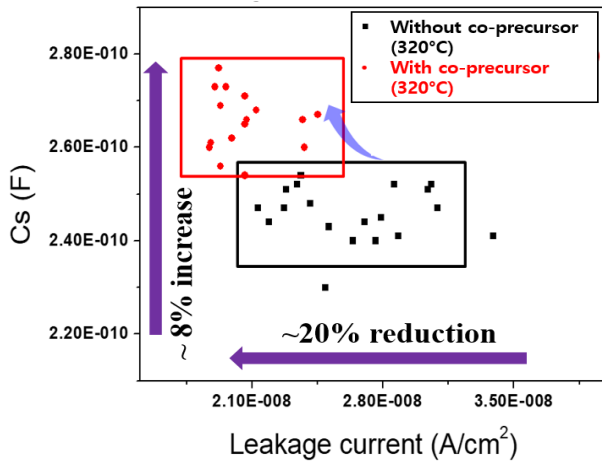


Fig. 2a: Comparison of the electrical performances (capacitance, Cs and leakage current) of HfO₂ film (with and without co-precursor)

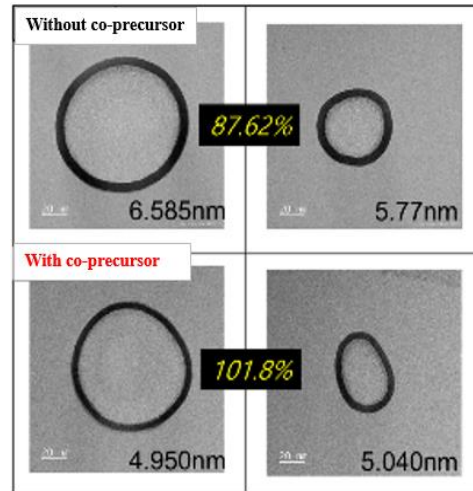


Fig. 2b: Comparison of the step coverage of HfO₂ in 22.6:1 aspect ratio (A/R) feature (with and without co-precursor)

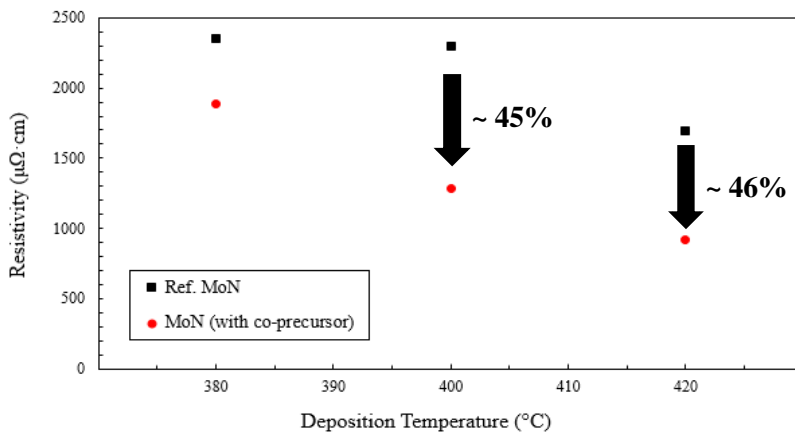


Fig. 3: Electrical resistivity of Ref. MoN_x (without co-precursor) and MoN_x (with co-precursor) at 380°C, 400°C and 420°C